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566.41191X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APR 30 2002

Applicant(s): KURATA, et al

Serial No.: 10/049,672

Filed: February 15, 2002

For: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL
POLISHING, AND METHOD OF POLISHING SUBSTRATE
MEMBER

International
Application No.: PCT/JP00/05508

International
Filing Date: August 17, 2000

Attention: PCT Branch

LETTER OF TRANSMITTAL

Commissioner for Patents
Washington, D.C. 20231

April 30, 2002

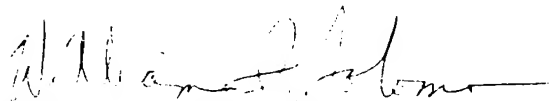
Sir:

In response to the Notification of Missing Requirements Under 35 U.S.C. 371 In the United States Designated/Elected Office (DO/EO/US) dated April 16, 2002, applicants are submitting herewith an executed Declaration. In addition, a payment in the amount of \$130.00 to cover the required surcharge for filing the declaration is also attached, in accordance with 37 CFR 1.492(e).

To the extent necessary, applicant's petition for an extension of time under 37 CFR 1.136. Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account

No. 01-2135 (566.41191X00) and please credit any excess fees
to such deposit account.

Respectfully submitted,



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Attachments
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